

WHAT IS CLAIMED IS:

1. An apparatus for processing a substrate, the apparatus comprising:
 - a housing having a processing space formed therein;
 - a support unit configured to support the substrate in the processing space;
 - a plasma generation unit located above the support unit and configured to supply plasma into the processing space;
 - a baffle disposed between the support unit and the plasma generation unit and configured to allow the plasma to pass through; and
 - a scatter disposed over the baffle and configured to separate the plasma and impurities, wherein the scatter includes:
 - a plate having a first opening formed in a central area thereof when viewed from above;and
 - a collision block configured to collide with the plasma supplied from the plasma generation unit and the impurities,
 - wherein the collision block includes inducing part disposed over the plate, overlapping the first opening when view from above, and having a larger diameter than the first opening.
2. The apparatus of claim 1, wherein the plate has a second opening formed in an edge area thereof when viewed from above.
3. The apparatus of claim 2, wherein the second opening has an arc shape when viewed from above.
4. The apparatus of claim 2, wherein a plurality of second openings are formed in the edge area of the plate and spaced apart from each other along a circumferential direction

of the plate.

5. The apparatus of claim 3 or 4, wherein an area between the first opening and the second opening(s) is provided as a blocking area.

6. The apparatus of claim 2, wherein the housing has an exhaust hole formed in the bottom thereof to release a gas from the processing space, and
wherein the exhaust hole, when viewed from above, is formed to overlap the second opening or formed outward of the second opening.

7. The apparatus of any one of claims 1 to 4, wherein the collision block includes a collision part disposed over the inducing part, and
wherein the collision part, when viewed in a vertical section, has a shape in which an upper end is downwardly inclined toward the outside from the center.

8. The apparatus of any one of claims 1 to 4, wherein the collision block includes a guide part disposed under the inducing part, and
wherein the guide part is inserted into the first opening.

9. The apparatus of claim 8, wherein the guide part, when viewed in a vertical section, has a shape in which a lower end is downwardly inclined toward the center from the outside.

10. The apparatus of any one of claims 1 to 4, wherein the baffle has a plurality of holes formed therein and includes an upper surface and a lower surface when viewed in a

vertical section, and

wherein the upper surface is formed to be a curved surface.

11. The apparatus of claim 10, wherein the curved surface is bent to be convex upward.